the BSA microscopes are activated, if not the Top Side Microscopes are activated. You can adjust the microscope light levels by switching the light switch knob to either Top Side or Back Side (located in the middle of the front pannel). Use the two knobs below and to the left of the Light Switch Knob for the Backside Microscope light levels and the Knob directly below the Light Switch Knob for the Top Side Microscopes light levels. Use the SPLITFIELD switch (located on the left side of the front pannel) to switch for one side microscope or both. Use the GRAB IMAGE key (located near the bottom left of key pad) to grab an image of the mask before you load your sample when doing Back Side Aligning.

Exposure:
Press the exposure key (located in the top middle of the key pad) to expose the resist coated wafer. The wafer moves into the exposure position and is exposed. Depending on the exposure program selected all program steps will be performed automatically. After finishing the exposure process the wafer chuck moves down to unload the exposed wafer.

Unload Wafer:
Wait until the message on the LCD screen appears “UNLOAD SUBSTRATE FROM SLIDE”. Pull trasport slide out completely. Unload wafer and move transport slide into aligner.

Unload Mask:
Press the CHANGE MASK key and the mask holder will be released. Pull the mask holder out and flip it 180 degrees and place it onto the tray on the left side of the system. Press the ENTER key to turn the mask vacuum off. Retract the mechanical clamp and remove the mask. Press the CHANGE MASK key and then press the ENTER key to clear the error. The tool can be left in this mode.